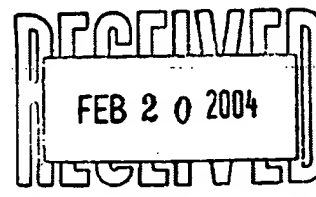


IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No.09/212,726
Filing Date December 15, 1998
Inventor Klaus F. Schuegraf
Assignee Micron Technology, Inc.
Group Art Unit 2813
Examiner Kielin, Erik J.
Attorney's Docket No.MI22-1098
Title: Semiconductor Processing Methods of Chemical Vapor Depositing SiO₂ on a
Substrate

RESPONSE TO OCTOBER 17, 2003 FINAL OFFICE ACTION
TO ACCOMPANY RCE FILING

To: Mail Stop RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450



From: Jennifer J. Taylor, Ph.D. (Tel. 509-624-4276; Fax 509-838-3424)
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AMENDMENTS

Introductory Comments

In reply to the final office action dated October 17, 2003, applicant amends and
remarks as follows.